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MS RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Dated: June 14, 2007

Signature:

Jo-Ann Bergantino
(Jo-Ann Bergantino)

Docket No.: 007734 FPS/MMCS/APC
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Young J. PAIK

Confirmation No.: 6290

Application No.:

10/665,165

Art Unit: 1763

Filed:

September 18, 2003

Examiner: S. MacArthur

Title: FEEDBACK CONTROL OF A CHEMICAL MECHANICAL POLISHING
PROCESS FOR MULTI-LAYERED FILMS

MS RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND REQUEST FOR CONTINUED EXAMINATION PURSUANT TO
37 C.F.R. § 1.114

Dear Sir:

Applicants hereby request continued examination of this application according to 37 C.F.R. § 1.114 by filing a submission (this Amendment) and the required fee set forth in § 1.17(e).

This communication addresses issues raised in the Office Action mailed June 16, 2006. Please amend the above-identified application as follows.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.